

Surface electron accumulation and effective mass anisotropy in wurtzite structure InN



UNIVERSITY OF NEBRASKA-LINCOLN



ThP.123

T. Hofmann¹, H. Lu², W.J. Schaff², V. Darakchieva³, and M. Schubert¹

¹ Department of Electrical Engineering and Nebraska Center for Materials and Nanoscience, University of Nebraska-Lincoln, U.S.A.

² Department of Electrical and Computer Engineering, Cornell University, U.S.A

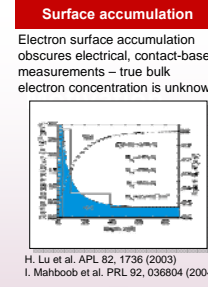
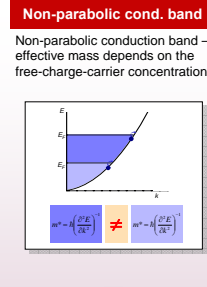
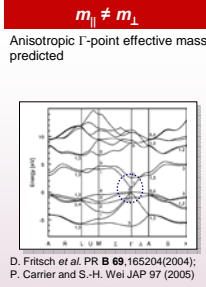
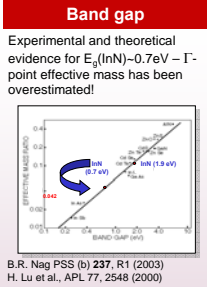
³ Department of Physics, Chemistry and Biology, Linköping University, Sweden

ellipsometry.unl.edu
thofmann@engr.unl.edu

Our message

- MO generalized ellipsometry measurements show evidence for a thin electron accumulation layer and corroborate HREELS and C-V data
- bulk and surface electron concentration follow power law dependencies as a function of the InN layer thickness
- strong deviation of scaling factors of the true bulk electron concentration and counted dislocation densities suggests evidence for a new defect related doping mechanism – most likely point defects, previously thought to be thickness independent
- neutralization of surface donors might be easier for low background concentrations
- experimental evidence for α -InN Γ -point effective electron mass value for polarization perpendicular to c-axis: $m_{\perp} = 0.050 \pm 0.03 m_0$ and $m_{\parallel} = 0.037 \pm 0.03 m_0$

Motivation: electronic properties of InN



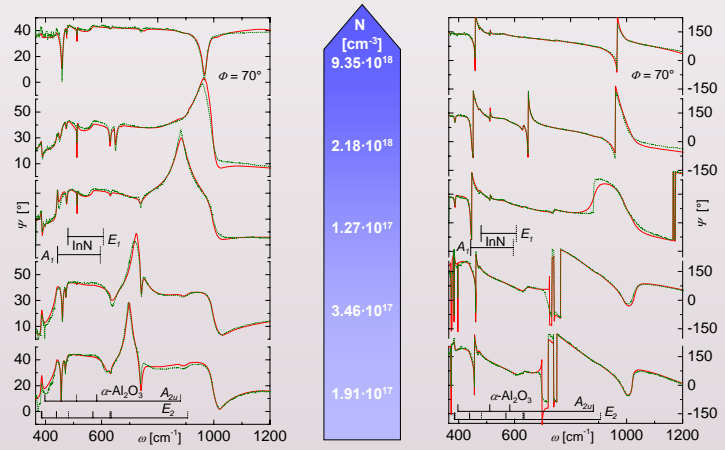
Far-infrared magneto-optic generalized ellipsometry

contact less, non-destructive determination of phonon and free-charge-carrier parameters (concentration, effective mass, mobility) in thin layer samples by stratified dielectric model calculation.

Recent publications on mo generalized ellipsometry:

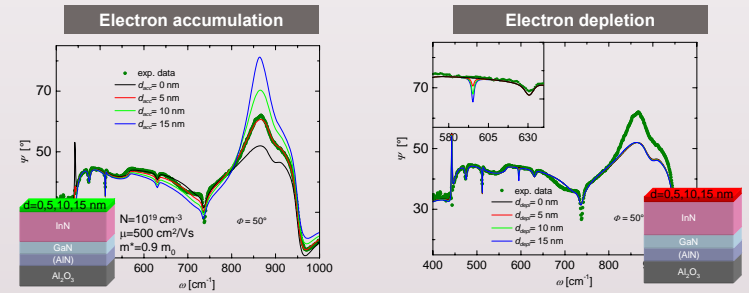
- T. Hofmann et al. Appl. Phys. Lett. (2007)
- T. Hofmann et al. Rev. Sci. Instrum. 77, 063902 (2006)
- M. Schubert et al. Thin Solid Films 465-466, 563-570 (2004)
- T. Hofmann et al. Mat. Res. Soc. Symp. Proc. 744, MS32-1-6 (2003)
- T. Hofmann et al. Appl. Phys. Lett. 82, 3463-3465 (2003)
- M. Schubert et al. J. Opt. Soc. Am. A 29, 347-356 (2003)

Standard ellipsometry (zero-magnetic-field)



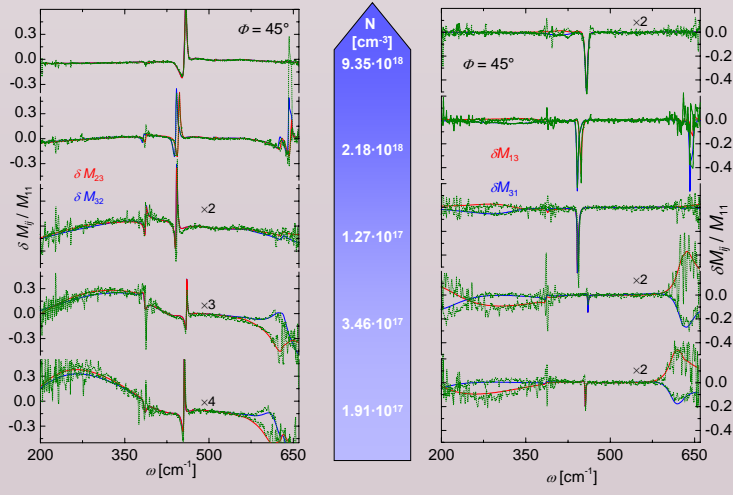
Zero-field ellipsometry spectra reveal thickness, phonon mode frequency and broadening parameters, static dielectric constants, plasma frequency and plasma broadening parameters of InN and GaN layers.

Electron surface accumulation or depletion?



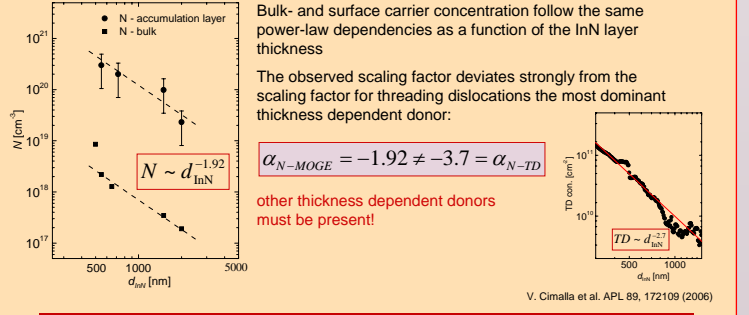
Fingerprints of a thin electron accumulation/depletion layer in wurtzite InN. Model calculations show distinct changes in the ellipsometric spectra if a charge depletion or accumulation layer is present. HREELS and C-V measurements have been reported in the literature. PR B 69, 201307(R) (2004); JCG 269, 29 (2004); PRL 92, 036804 (2004); APL 82, 1736 (2003)

Magneto-optic generalized ellipsometry



Differences between Mueller matrix data (chiral elements M_{13} , M_{31} , M_{22} , and M_{23}) measured magnetic fields of +4.5T and -4.5T. The non-chiral elements M_{12} , M_{21} , M_{22} , and M_{33} vanish.

Bulk- and surface carrier properties



Anisotropic Γ -point effective mass

